

1 Inventor: Klaus F. Schuegraf

2 Title: Semiconductor Processing Methods of Chemical Vapor  
3 Depositing SiO<sub>2</sub> on a Substrate

4 Assignee: Micron Technology, Inc.

5  
6 INFORMATION DISCLOSURE STATEMENT

7  
8 References -- See Attached Form PTO-1449

9 The attached form PTO-1449 is submitted in compliance  
10 with 37 CFR §1.56. No admission is made regarding whether all the  
11 submitted references are prior art.

12 Respectfully submitted,

13  
14 Dated: 12/15/98

Attorney: 

Lance R. Sadler

Reg. No.: 38,605

WELLS, ST. JOHN, ROBERTS,  
GREGORY & MATKIN P.S.

601 W. First Ave., Suite 1300

Spokane, WA 99201-3828

(509) 624-4276

jc549 U.S. PTO

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